



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535  
First Named Inventor : Takuya SUGAWARA  
Filed : June 28, 2004  
TC/A.U. : 2823  
Examiner : M. Estrada  
  
Docket No. : 010986.55104US  
Customer No. : 23911  
  
Title : Substrate Treating Method and Production Method for  
Semiconductor Device

**REPLY**

**Mail Stop AMENDMENT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in response to the non-final Office Action dated July 25, 2006.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.